

East % USPB, USPT, WIPO, JPO

L Number	Hits	Search Text	DB	Time stamp
1	2174010	etch\$ or patern\$ or remov\$	USPAT; US-PGPUB	2004/05/25 11:09
2	182347	(two or dual) with step?	USPAT; US-PGPUB	2004/05/25 11:09
3	11137	(etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?	USPAT; US-PGPUB	2004/05/25 10:02
4	38993) high with (k or dielectric?)	USPAT; US-PGPUB	2004/05/25 11:09
5	27016	overetch\$ or oe	USPAT; US-PGPUB	2004/05/25 11:10
6	1316	(high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)	USPAT; US-PGPUB	2004/05/25 11:10
7	351180	(multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)	USPAT; US-PGPUB	2004/05/25 11:10
8	534694	(1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?	USPAT; US-PGPUB	2004/05/25 11:10
9	145662	(etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)	USPAT; US-PGPUB	2004/05/25 10:07
10	11137	(etch\$ or patern\$ or remov\$) with ((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?))	USPAT; US-PGPUB	2004/05/25 10:09
11	259	((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))	USPAT; US-PGPUB	2004/05/25 10:09
12	145899	(wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$)	USPAT; US-PGPUB	2004/05/25 11:31
13	64	((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same ((wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$))	USPAT; US-PGPUB	2004/05/25 10:11
14	58420	sac or (self with align\$)	USPAT; US-PGPUB	2004/05/25 11:32
15	19	((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same (sac or (self with align\$))	USPAT; US-PGPUB	2004/05/25 10:12
16	34	((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same align\$	USPAT; US-PGPUB	2004/05/25 10:12

17	63	((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same ("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4"))	USPAT; US-PGPUB	2004/05/25 11:32
18	113	(((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same ((wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$ or (reactive with ion)) with (etch\$ or patern\$ or remov\$))) or (((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same align\$) or (((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same align\$) or (((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same ("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4"))	USPAT; US-PGPUB	2004/05/25 10:16

19	146	(((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) not (((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same ((wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$))) or (((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same (sac or (self with align\$)) or (((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same align\$) or (((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) same (((etch\$ or patern\$ or remov\$) WITH ((two or dual) with step?)) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) same ("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4"))))	USPAT; US-PGPUB	2004/05/25 10:47
20	1592356	etch\$ or patern\$ or remov\$	JPO; DERWENT	2004/05/25 11:29
21	7865	high with (k or dielectric?)	JPO; DERWENT	2004/05/25 11:09
22	22914	(two or dual) with step?	JPO; DERWENT	2004/05/25 11:09
23	12893	overetch\$ or oe	JPO; DERWENT	2004/05/25 11:10
24	74192	(multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)	JPO; DERWENT	2004/05/25 11:10
25	352	(high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)	JPO; DERWENT	2004/05/25 11:10
26	29290	(1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?	JPO; DERWENT	2004/05/25 11:11
27	818	(etch\$ or patern\$ or remov\$) and (high with (k or dielectric?))	JPO; DERWENT	2004/05/25 11:12
28	4033	(etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)	JPO; DERWENT	2004/05/25 11:15
29	68	((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$)) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?))))	JPO; DERWENT	2004/05/25 11:30

30	197974	ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5"	JPO; DERWENT	2004/05/25 11:29
31	7507	(etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")	JPO; DERWENT	2004/05/25 11:29
32	7493	((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))	JPO; DERWENT	2004/05/25 11:29
33	657	((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))	JPO; DERWENT	2004/05/25 11:30
34	0	(wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$)	JPO; DERWENT	2004/05/25 11:31
35	65139	(wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$)	JPO; DERWENT	2004/05/25 11:31
36	80	(((((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$))	JPO; DERWENT	2004/05/25 11:32
37	20823	sac or (self with align\$)	JPO; DERWENT	2004/05/25 11:32
38	630374	("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4"))	JPO; DERWENT	2004/05/25 11:33
39	332522	align\$	JPO; DERWENT	2004/05/25 11:33
40	78	(((((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((sac or (self with align\$)) or (("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4")))) or align\$)	JPO; DERWENT	2004/05/25 11:33

41	150	(((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$))) or (((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((sac or (self with align\$)) or ("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4")) or align\$))	JPO; DERWENT	2004/05/25 12:00
42	507	(((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) not (((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$))) or (((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((sac or (self with align\$)) or ("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4")) or align\$)))	JPO; DERWENT	2004/05/25 12:00

43	507	(((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) not ((((((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$))) or ((((((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((sac or (self with align\$)) or (("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4")))) or align\$)))	JPO; DERWENT	2004/05/25 12:00
44	55	(((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) not ((((((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((wet or dry or plasma? or sputter\$ or corona? or rie or mrie or merie or (glow with discharg\$) or (reactive with ion)) with (etch\$ or patern\$ or remov\$))) or ((((((etch\$ or patern\$ or remov\$) with (ferroelect\$ or hafnium or zirconium or alumina or titanate or tantalum or bst or pzt or plzt or "hf2o3" or "zr2o3" or "ta2o5")) not ((high with (k or dielectric?)) with (etch\$ or patern\$ or remov\$))) and (((two or dual) with step?) or (overetch\$ or oe) or ((multi(w)step? or multistep? or over) with (etch\$ or patern\$ or remov\$)) or ((etch\$ or patern\$ or remov\$) with ((1st or 2nd or first or second or (etch\$ or patern\$ or remov\$) st or ((two or dual) with step?) nd) with step?)))) and ((sac or (self with align\$)) or (("h2so4" or sulfuric or ash\$ or strip\$ or spacer? or hf or hydrofluoric or ("h.sub.2" with "so.sub.4")))) or align\$)))) and (resist or photoresist or mask or photomask)	JPO; DERWENT	2004/05/25 12:00